

FEAA128: Model Based Property Prediction of Ni-based Components Fabricated by Additive Manufacturing

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Background/Objectives

- Develop/improve physics-based simulation tools to describe all steps of the AM process
- Use simulation + real-time process monitoring to establish correlation between process-structure-property and "locally" control the alloy properties

Grain structure prediction



In-situ Crack detection via Near IR In-situ

Improving Approach/Physic-Based Models For Process-Microstructure-Properties Correlation



New Point Net Beam Strategies to Control Thermal Gradients, Solidification Rates and Microstructures



Controlling the Microstructure to Reduce EBM282 Creep Anisotropy at 800°C



Superior creep strength with columnar grains along the build direction (BD) but significant creep strength decrease perpendicular to BD



Variation of Fatigue Crack Growth in EBM 282 Composite Microstructure

Constant $\Delta K=20$ ksi*in^{0.5} tests Paris Law: da/dN = C(ΔK)ⁿ Hence da/dN = f(<u>microstructure</u> <u>alone</u>)

2X da/dN change across microstructures



ΒD





Crystal Plasticity Model Reveals Microstructure Influence on Fatigue Crack Propagation ^{Simulated microstructure}

 Crystal plasticity finite element model (CPFEM) predicts the effect of grain size, grain morphology and texture on the heterogeneous deformation in the microstructure

Distribution of stress under applied load of 320MPa





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Crystal Plasticity Model Predicts Different Crack Propagation Paths for Coarse and Fine Regions



CPFEM simulated crack path

Fractography of fatigue crack surfaces

Demonstrate opportunity for local control of properties through microstructure control for complex components Crack surface in coarse region



Crack surface in fine region

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Synthetic Microstructure to Accelerate Process-Microstructure-Performance Correlation

Process-Microstructure

Using Kinetic Monte Carlo Model

1.Melt Pool Shape



Conversion from KMC to FEM

Uniaxial Loading



Microstructure-Performance

high



Grain Rotation

Low



Machine Learning Surrogate Model for Emulating AM Nibase Superalloy Viscoplastic Behavior





ANN model captures strength-texture dependence

- Addition of cube slip systems in viscoplastic self-consistent (VPSC) code can explain observed mechanical anisotropy
- ANN emulates the VPSC model (or CPFEM model) to predict mechanical properties based on anisotropic crystallographic texture



Source Stational Laboratory

Equiaxed Grain Clusters Found in AM Microstructures Results in Local Strain concentration



Creep properties anisotropy likely related to crystallographic texture and heterogenous stray grains leading to local stress concentration

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Extract Maximum Constitutive Information From Experiments Utilizing Correlation Statistics



- Successful estimate of strain from microstructure
- Tools can be used for microstructure/properties or damage correlation for tensile, creep, fatigue, oxidation, etc.



Understanding Crack Formation in High Gamma Prime Alloys for Crack-free Components



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Cracking Prediction during AM Process

Hot cracking susceptibility



Developing Advanced Sensor & Machine Learning Architecture for Near Real-Time Process Control



Stainless steel plates usea as backscattered **electron** detectors (BSE)





Conclusion/Future Work

• Significant progress in developing modeling/data analytics tools for process-microstructure-properties correlation



- Add complexity to the synthetic microstructure i.e. precipitates
- Upgrade/modify tools for large scale AM
- AM Microstructure control for specific application (e.g. H)

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